# Monthly LabAdviser update: 20/12 2016

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| Updated Subject | Contributor | Link to the updated pages |
| **SiO2 etch with DUV mask on 150mm wafers using ICP metal** | **Zhibo Li @danchip** | <http://labadviser.danchip.dtu.dk/index.php/Specific_Process_Knowledge/Etch/ICP_Metal_Etcher/silicon_oxide#SiO2_etch_using_DUV_mask> |
| **News in LabAdviser:**  **Slides from the customer meeting December 2016** | **Anders M. Jørgensen @danchip** | <http://labadviser.danchip.dtu.dk/index.php/Main_Page> |

# Equipment Manuals updated in LabManager:

As an approved user on a piece of equipment you have to make sure you have read and understood the latest version of the manual before using the equipment.

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| |  | | --- | | **APV and manual for fumehoods in B-1. F-3 and C-1** | | **Manual for Electroplating-Ni (Technotrans microform.200)** | | **Manual for Si Etch 3: KOH** | |
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